



IFW/

Docket No. 0524-0139.01

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re Application of: )  
)  
Nozawa et al. )  
)  
Serial No.: 10/771,997 )  
)  
Filed: February 4, 2004 )  
)  
For: Manufacturing Method And Apparatus of )  
Phase Mask Shift Blank )  
)  
Examiner: Steven Versteeg )  
)  
Art Unit: 1753 )

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to:  
Commissioner for Patents,  
P.O. Box 1450, Alexandria, VA 22313-1450 on

January 13, 2005  
(Date of Deposit)

Shannon Wallace

Name of applicant, assignee, or Registered Rep.  
Shannon Wallace 1/13/05  
Signature Date

AMENDMENT A

Commissioner of Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action of September 13, 2004, a one month extension of time be  
being submitted herewith, please amend the above-identified application as follows: